

## Supporting Information

### Grain Boundary Induced Bias Instability in Soluble Acene-Based Thin-Film Transistors

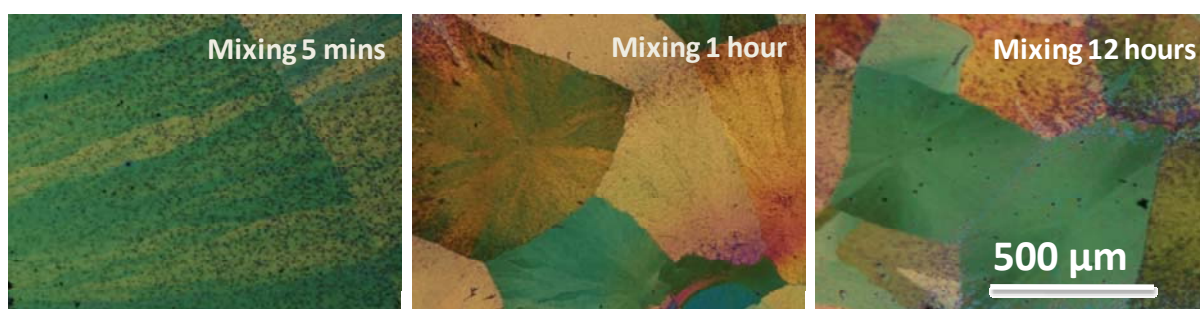
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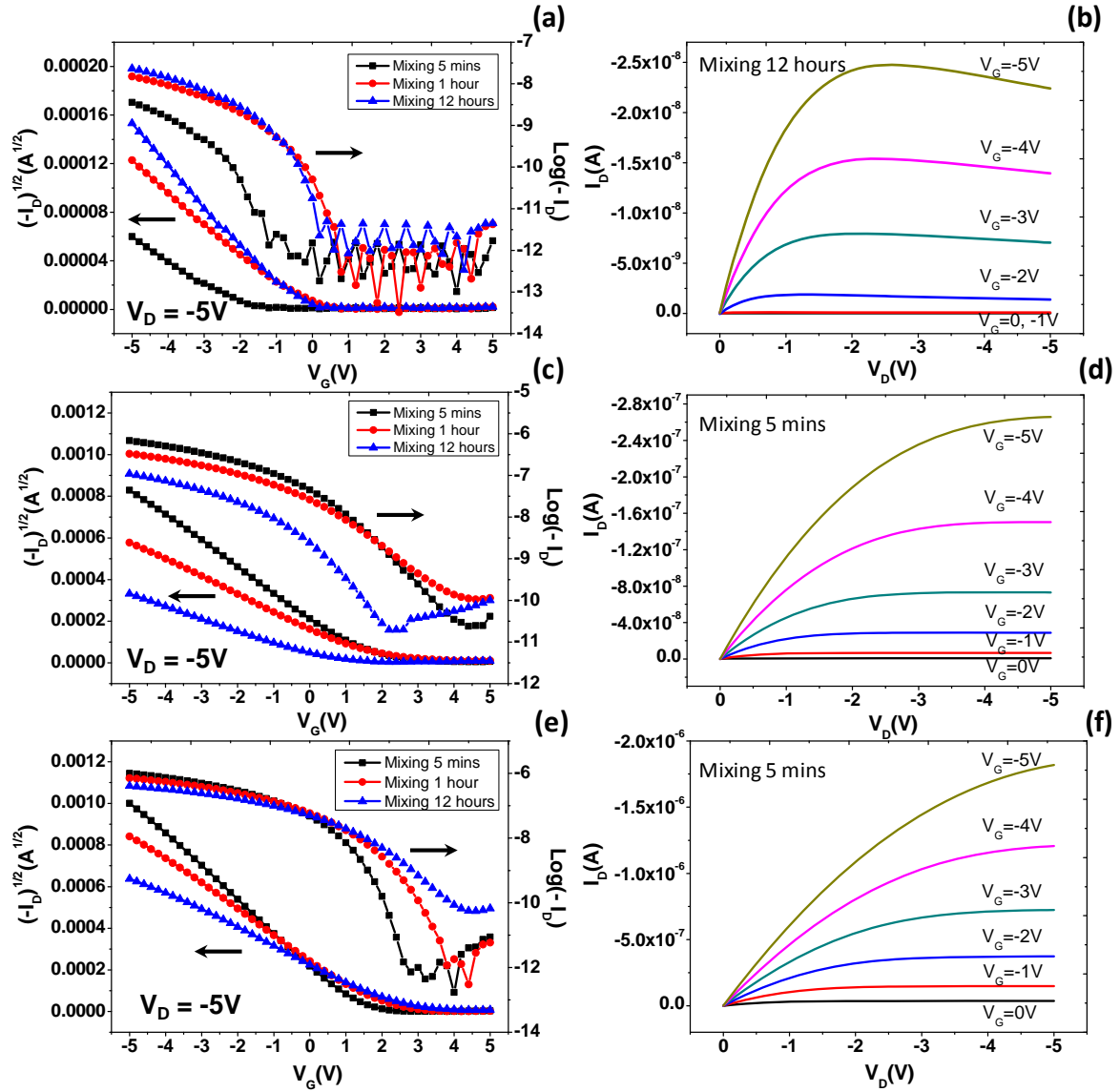
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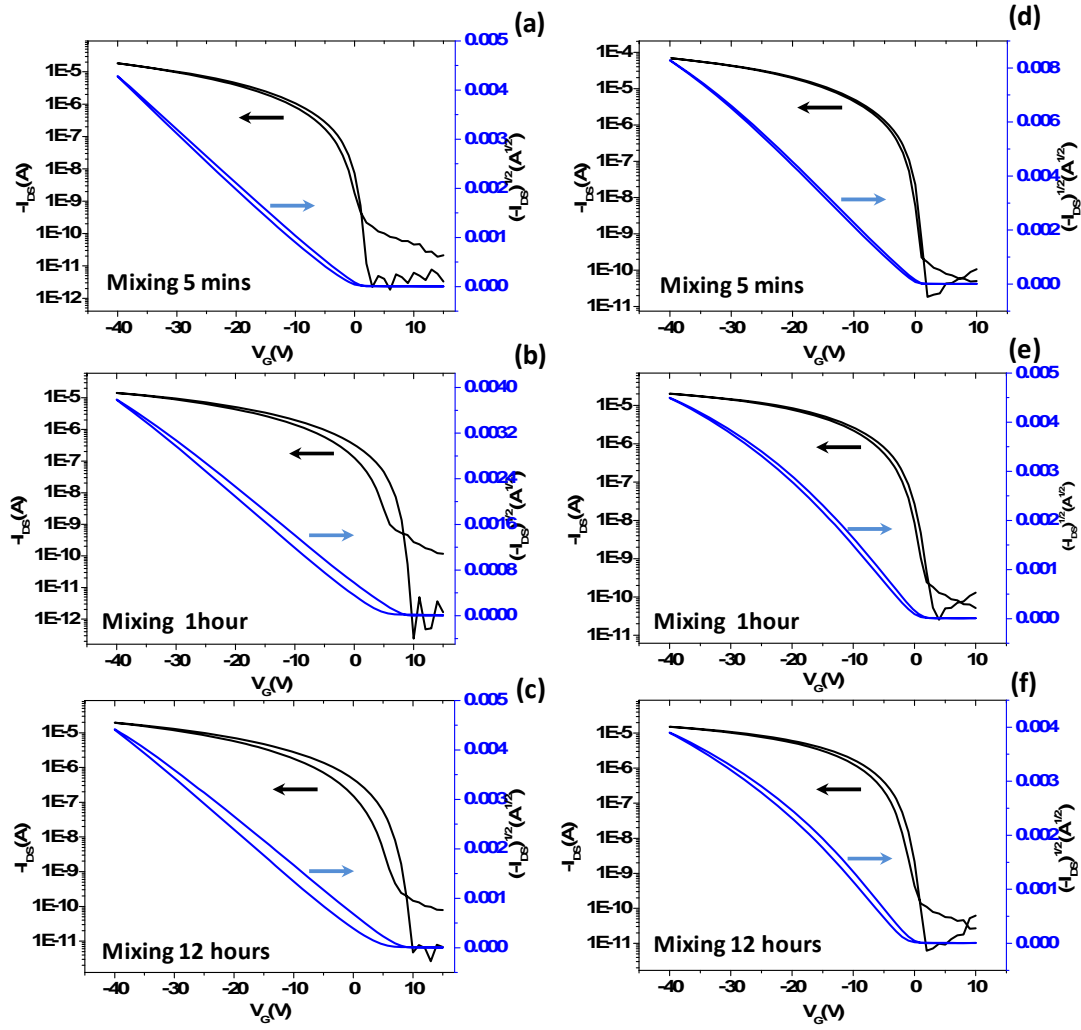
**Figure S1.** Polarized optical micrographs of the channel regions of TES-ADT FETs with different grain boundaries.



**Figure S2.** Polarized optical micrographs of TES-ADT films based on PS brush-treated SiO<sub>2</sub> dielectric after solvent vapor annealing.



**Figure S3.** Typical transfer and output characteristics of TES-ADT FETs at low gate and source/drain biases ( $V_G = -5$  V,  $V_D = -5$  V). Before solvent annealing (a, b). An untreated  $\text{SiO}_2$  dielectric after solvent vapor annealing (c, d). A PS brush-treated  $\text{SiO}_2$  dielectric after solvent vapor annealing (e, f).



**Figure S4.** Hysteresis characteristics of TES-ADT FETs at  $V_D = -40$  V. An untreated  $SiO_2$  dielectric after solvent vapor annealing (a, b, c). A PS brush-treated  $SiO_2$  dielectric after solvent vapor annealing (d, e, f).

**Table S1.** Electrical properties of TES-ADT transistors before and after solvent vapor annealing at low gate and source/drain biases ( $V_G = -5V$ ,  $V_D = -5V$ ).

Devices	Mixing time	Mobility ( $\text{cm}^2\text{V}^{-1}\text{s}^{-1}$ )	$V_{th}$ (V)	$I_{on} / I_{off}$
Untreated $\text{SiO}_2$ Before solvent annealing	5 mins	$0.75 \times 10^{-2}$ $\pm 0.002$	-2.09	$1.0 \times 10^3$
	1 hour	$1.24 \times 10^{-2}$ $\pm 0.0008$	-0.60	$1.0 \times 10^4$
	12 hours	$2.15 \times 10^{-2}$ $\pm 0.0045$	-0.99	$1.0 \times 10^4$
Untreated $\text{SiO}_2$ After solvent annealing	5 mins	$0.199 \pm 0.019$	1.40	$1.0 \times 10^4$
	1 hour	$0.110 \pm 0.007$	2.32	$1.0 \times 10^4$
	12 hours	$0.097 \pm 0.010$	0.52	$1.0 \times 10^4$
PS brush After solvent annealing	5 mins	$0.779 \pm 0.070$	1.30	$1.0 \times 10^6$
	1 hour	$0.308 \pm 0.040$	2.18	$1.0 \times 10^5$
	12 hours	$0.253 \pm 0.034$	2.72	$1.0 \times 10^4$